

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No.: 7829
Koichiro TANAKA) Examiner: Maria A. Elve
Serial No. 10/721,075) Group Art Unit: 3742
Filed: November 26, 2003)
For: LASER IRRADIATION APPARATUS,)
LASER IRRADIATION METHOD,)
AND METHOD FOR)
MANUFACTURING A)
SEMICONDUCTOR DEVICE)

AFTER FINAL RESPONSE

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The Official Action mailed March 16, 2010, has been received and its contents carefully noted. This response is filed within three months of the mailing date of the Official Action and therefore is believed to be timely without extension of time. Accordingly, the Applicant respectfully submits that this response is being timely filed.

The Applicant notes with appreciation the consideration of the Information Disclosure Statements filed on November 26, 2003; January 8, 2004; January 20, 2004; February 3, 2004; September 29, 2005; April 3, 2006; October 19, 2007; April 9, 2008; and May 15, 2009.

Claims 1, 2, 4-11, 13-20, 22-29, 31-38, 40-47 and 49-54 are pending in the present application, of which claims 1, 10, 19, 28, 37 and 46 are independent. For the reasons set forth in detail below, all claims are believed to be in condition for allowance. Favorable reconsideration is requested.